

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L15	1026536	wafer or substrate	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L16	635234	semi\$1conductor	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L17	1133958	storing or store or storage	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L18	53069	electro\$1plat\$3 or electro\$1deposit\$1	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L19	70379	electro\$polish\$3 or CMP or (chemical mechanical polishing)	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L20	729448	clean\$3 or cleans\$3	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L21	203897	(robot or computer) with (transfer\$4 or transpor\$4 or mov\$3)	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L22	239858	L15 near3 L16	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L23	18046	L17 with L15	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L24	1786	L19 same L18 same L15	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L25	45	L22 and L23 and L24 and L20 and L21	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
L26	5	L25 and (align\$4 with wafer)	US-PGPUB; USPAT	ADJ	ON	2007/05/08 13:38
L27	236	robot with remov\$4 with (roll\$3 or slid\$3)	US-PGPUB; USPAT	ADJ	ON	2007/05/08 13:38
L28	75401	"204".clas. or "205".clas.	US-PGPUB; USPAT	ADJ	ON	2007/05/08 13:38
L29	2	L27 and L28	US-PGPUB; USPAT	ADJ	ON	2007/05/08 13:48
L30	1	robot with (sliding near3 out) with (section or chamber or module)	US-PGPUB; USPAT	ADJ	ON	2007/05/08 13:49
L31	14	robot with (sliding near3 out)	US-PGPUB; USPAT	ADJ	ON	2007/05/08 13:57
L32	369	robot with removable	US-PGPUB; USPAT	ADJ	ON	2007/05/08 13:57
L33	7	L32 with out	US-PGPUB; USPAT	ADJ	ON	2007/05/08 14:00
L34	6	robot with detachable with wafer	US-PGPUB; USPAT	ADJ	ON	2007/05/08 14:23

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L35	158	robot with end\$1effectors	US-PGPUB; USPAT	ADJ	ON	2007/05/08 14:23
L36	26	I35 with second	US-PGPUB; USPAT	ADJ	ON	2007/05/08 14:42
L37	1088	surge suppressor	US-PGPUB; USPAT	ADJ	ON	2007/05/08 14:42
L38	75401	"204".clas. or "205".clas.	US-PGPUB; USPAT	ADJ	ON	2007/05/08 14:42
L39	10	I37 and I38	US-PGPUB; USPAT	ADJ	ON	2007/05/08 14:51
L40	21654	controller with flow with rate	US-PGPUB; USPAT	ADJ	ON	2007/05/08 14:52
L41	600	I38 and I40	US-PGPUB; USPAT	ADJ	ON	2007/05/08 14:52
L42	235	I41 and wafer	US-PGPUB; USPAT	ADJ	ON	2007/05/08 14:52
L43	6	I42 and process adj liquid	US-PGPUB; USPAT	ADJ	ON	2007/05/08 17:35
S90 5	1025712	wafer or substrate	US-PGPUB; USPAT	ADJ	ON	2007/05/07 15:46
S90 6	634618	semi\$1conductor	US-PGPUB; USPAT	ADJ	ON	2007/05/07 15:47
S90 7	1132995	storing or store or storage	US-PGPUB; USPAT	ADJ	ON	2007/05/07 15:50
S90 8	53033	electro\$1plat\$3 or electro\$1deposit\$1	US-PGPUB; USPAT	ADJ	ON	2007/05/07 15:50
S90 9	70295	electro\$polish\$3 or CMP or (chemical mechanical polishing)	US-PGPUB; USPAT	ADJ	ON	2007/05/07 15:51
S91 0	729042	clean\$3 or cleans\$3	US-PGPUB; USPAT	ADJ	ON	2007/05/07 15:51
S91 1	203704	(robot or computer) with (transfer\$4 or transpor\$4 or mov\$3)	US-PGPUB; USPAT	ADJ	ON	2007/05/07 15:55
S91 2	1	S905 with S906 with S907 with S908 with S909 with S910 with S911	US-PGPUB; USPAT	ADJ	ON	2007/05/07 15:56
S91 3	311	S905 and S906 and S907 and S908 and S909 and S910 and S911	US-PGPUB; USPAT	ADJ	ON	2007/05/07 16:02
S91 4	239656	S905 near3 S906	US-PGPUB; USPAT	ADJ	ON	2007/05/07 16:03
S91 5	18031	S907 with S905	US-PGPUB; USPAT	ADJ	ON	2007/05/07 16:04
S91 6	1784	S909 same S908 same S905	US-PGPUB; USPAT	ADJ	ON	2007/05/07 16:04

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S91 7	825	cleaning module	US-PGPUB; USPAT	ADJ	ON	2007/05/07 16:04
S91 8	4	S914 and S915 and S916 and S917 and S911	US-PGPUB; USPAT	ADJ	ON	2007/05/07 16:07
S91 9	45	S914 and S915 and S916 and S910 and S911	US-PGPUB; USPAT	ADJ	ON	2007/05/08 12:58
S92 0	21	(US-20050260933-\$ or US-20040245214-\$ or US-20040163947-\$ or US-20040069646-\$ or US-20020124906-\$ or US-20020056647-\$ or US-20020005359-\$ or US-20010029150-\$ or US-20010024691-\$).did. or (US-6884334-\$ or US-6689257-\$ or US-6352623-\$ or US-5516414-\$ or US-7060618-\$ or US-6935932-\$ or US-6813032-\$ or US-6758876-\$ or US-6721045-\$ or US-6707545-\$ or US-6632335-\$ or US-6630995-\$). did.	US-PGPUB; USPAT	ADJ	ON	2007/05/07 17:07
S92 1	12	S920 and (remov\$3 with robot)	US-PGPUB; USPAT	ADJ	ON	2007/05/07 17:12
S92 2	6	S920 and ((wafer or substrate) same (align\$4))	US-PGPUB; USPAT	ADJ	ON	2007/05/07 17:13